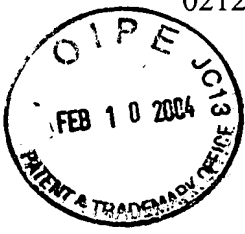


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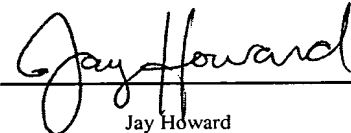


IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of: Jacque C.S. Kools et al.
Date Filed: November 12, 2003
Serial No.: 10/706,637
Examiner: Unknown
Title: *Method and Apparatus for Fabricating a Conformal Thin Film on a Substrate*

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

I hereby certify that this Information Disclosure Statement is being deposited with the United States Postal Service as Express Mail No. **EV352391129US** addressed to: Box: Commissioner for Patents, Alexandria, VA 22313-1450, on February 10, 2004.


Jay Howard

Dear Sir:

INFORMATION DISCLOSURE STATEMENT

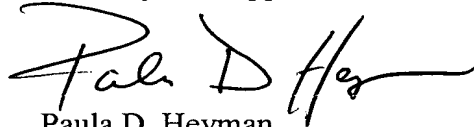
Applicants respectfully request, pursuant to 37 C.F.R. §§1.56, 1.97, and 1.98, that the references listed on the attached PTO-1449 form be considered and cited in the examination of the above-identified application. Copies of the references are enclosed for the convenience of the Examiner. Since the present Application was filed after June 30, 2003, a copy of any U.S. Patent and any U.S. Patent Application Publication cited on the attached PTO Form 1449 is not being submitted with this Information Disclosure Statement pursuant to the July 11, 2003 waiver of 37 C.F.R. S 1.98(a)(2)(i) by the U.S. Patent and Trademark Office.

Furthermore, pursuant to 37 C.F.R. §§1.97 (g) and (h), no representation is made that these references are material to the patentability of the present application.

Applicants believe no fees are due, however, the Commissioner is hereby authorized to charge any fee to Deposit Account No. 50-2148 of Baker Botts L.L.P. in order to effectuate this filing.

Respectfully submitted,

BAKER BOTTS L.L.P.
Attorneys for Applicants



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PTO-1449 Information Disclosure Citation in an Application	Application No.		Applicant(s)	
	10/706,637		Jacque C.S. Kools et al.	
	Docket Number	Group Art Unit	Filing Date	
	021208.0247	Unknown	11/12/2003	

U.S. PATENT DOCUMENTS

	DOCUMENT NO.	DATE	NAME	CLASS	SUBCLASS	FILING DATE
A.	5647911	07/15/97	Vanell et al.	118	715	12/14/93
B.	5711811	01/27/98	Suntola et al.	118	711	11/28/95
C.	5916369	06/29/99	Anderson et al.	118	715	06/07/95
D.	6387185 B2	05/14/02	Doering et al.	118	729	01/16/01
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G.						
H.						
I.						
J.						
K.						

FOREIGN PATENT DOCUMENTS

	DOCUMENT NO.	DATE	COUNTRY	CLASS	SUBCLASS	TRANSLATION	
						YES	NO
L.							
M.							
N.							
O.							
P.							

NON-PATENT DOCUMENTS

	DOCUMENT (Including Author, Title, Source, and Pertinent Pages)	DATE
Q.	Omstead, Thomas, et al.; "Filling High-AR Structures Using Pulsed Nucleation Layer Deposition", Solid State Technology, Vol. 45, pp. 51-56.	09/2002
R.	Ritala, Mikko, et al.; "Atomic Layer Epitaxy – a Valuable Tool for Nanotechnology?", Nanotechnology, Vol. 10, pp. 19-24.	1999
S.		
T.		
U.		

EXAMINER

DATE CONSIDERED

EXAMINER: Initial if citation considered, whether or not citation is in conformance with MPEP § 609. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to the applicant.